

SPECIFICATION**TITLE OF INVENTION****METHOD FOR TOOLMATCHING AND TROUBLESHOOTING A PLASMA PROCESSING SYSTEM****STATEMENT OF RELATED APPLICATION**

[0001] The present application is a continuation-in-part of U.S. Patent
Now Pat. No. 6,873,114
Application Serial No. 10/341,913, filed January 13, 2003, in the name of inventors
Armen Avoyan and Seyed Jafar Jafarian-Tehrani, entitled "Method for toolmatching and
troubleshooting a plasma processing system", commonly assigned herewith. U.S. Patent
Application Serial No. 10/341,913, filed January 13, 2003, claims the benefit of U.S.
Provisional Patent Application Serial No. 60/414,108, filed September 26, 2002, in the
name of inventors Armen Avoyan and Seyed Jafar Jafarian-Tehrani, commonly assigned
herewith.

FIELD OF THE INVENTION

[0002] The present invention relates to the fabrication of materials such as
electronic devices in plasma processing system. More particularly, the present invention
relates to a method and system for verifying the operation of a plasma processing system.